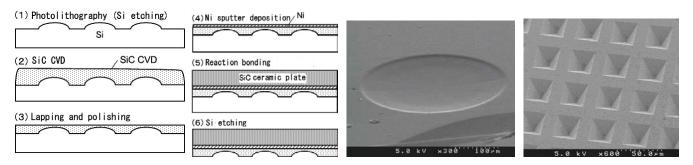
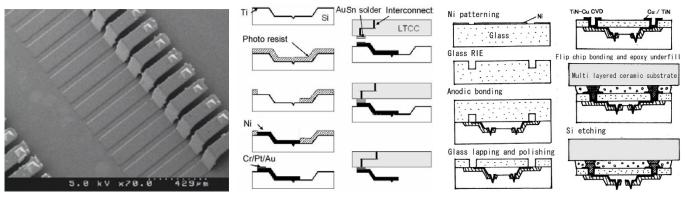
MEMS for production, testing, environment and safety

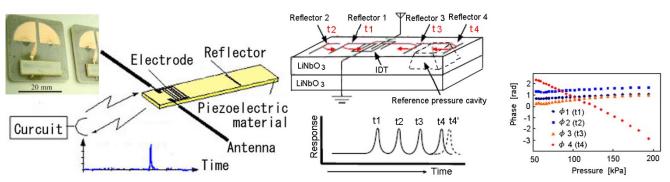


SiC mold Glass formed by press with SiC mold

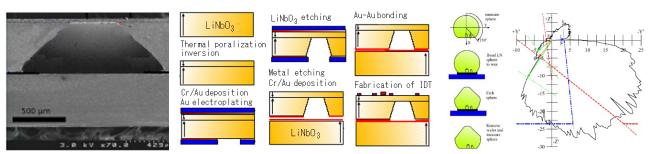
SiC mold for glass press molding (T.Itoh, J.of Microelectromechanical Systems, 15 (2006) 859)



Probe card for testing LSI wafer (S.-H.Choe et.al., IEEE Internl. Test Conf. 2007 (2007))



Surface Acoustic Wave (SAW) wireless passive sensor. Tire pressure monitoring system and its LiNbO₃ diaphragm (S.Hashimotoet.al(Nissan motor), Transaction of IEEJ, 128-E (2008) 231)



 $\mbox{LiNbO}_3 \mbox{ diaphragm and its fabrication process using thermal polarization.} \\ \mbox{inversion and anisotropic etching}$

Anisotropic etching of LiNbO₃ depending on crystal orientation.

(A.B.Randles et.al, Jap. J. of Applied Physics, 46,45 (2007) L1099-1101)

(A.B.Randles et.al, IEEE Trans. on Ultrasonics, Ferroelectrrics, and Frequency Control, 57, 11 (2010) 2372-2380)